

U.S. Department of Commerce, Patent and Trademark Office				Atty Docket No.		Serial No.	
				M-9131 US		Unknown	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Applicant			
(Use several sheets if necessary)				James M. Holden			
				Filing Date		Group	
				Herewith		Unknown	
U.S. Patent Documents							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
ah	AA	4,999,010	Mar. 12, 1991	Mattson et al.	356	346	—
ah	AB	6,075,612	Jun. 13, 2000	Mandella et al.	356	445	—
ah	AC	6,084,662	Jul. 4, 2000	Seaburn	356	73	—
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
Foreign Patent Documents							
							Translation
		Document	Date	Country	Class	Subclass	Yes No
ah	AL	WO 00/12961	9 Mar 2000	WFO PCT	—	—	✓
	AM						
	AN						
	AO						
	AP						
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
ah	AQ	Gamsky, C. et al., "Quantitative analysis of chemically amplified negative photoresist using mirror-backed infrared reflection absorption spectroscopy" SPIE Vol. 2438, Pages 143-152.					
ah	AR	Gamsky, C., "Reflectance FT-IR For Monitoring Chemical Reactions In Chemically Amplified Photoresists For 0.25 μ m X-Ray Lithography" UMI Dissertation Services, at the University of Wisconsin-Madison (1995), Pages 1-250.					
	AS						
Examiner		Date Considered					
Andrew Melvin		8/28/03					
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.							

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 08/06/01

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 R. Taylor

U.S. Department of Commerce, Patent and Trademark Office				Atty Docket No.		Serial No.	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)				M-9131 US		09/923,723	
Applicant				James M. Holden			
Filing Date				August 6, 2001		Group	
						Unknown	

U.S. Patent Documents							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
ah	AA	5,889,593	Mar. 30, 1999	Bareket	356	445	
	AB						
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	AH						
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	AJ						
	AK						

Foreign Patent Documents							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)		
ah	AQ	Harrison, D. et al., "Innovations in Lithography Metrology for Characterization of Phase-Shift Mask Materials" <i>SPIE</i> (2001) Pages 233-240.
ah	AR	"n&k Analyzer 1512RT", downloaded 9/25/01 from < http://www.nandk.com/1512rt.html >, n&k Technology, Inc. (2001).
	AS	

Examiner	Anadmerito	Date Considered	8/28/03
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.